



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Satyavolu S. Papa Rao, et al.

Docket No: TI-36640

Serial No: 10/689,218

Conf. No: 4083

Examiner: Evan T. Pert

Art Unit: 2829

Filed: 10/20/2003

For: MEASUREMENT OF WAFER TEMPERATURE IN SEMICONDUCTOR PROCESSING  
CHAMBERS

LETTER TO OFFICIAL DRAFTSPERSON

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Attention: Official Draftsperson

**MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)**

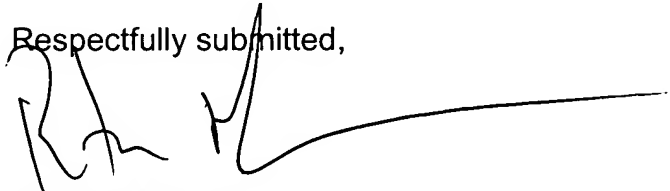
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 1-18-05.

  
Ann Trent

Dear Sir:

Transmitted herewith for filing are two sheets of formal drawings for the above identified application. Charge any necessary fees to the deposit account of Texas Instruments Incorporated, Account No. 20-0668.

Respectfully submitted,

  
Peter K. McLarty  
Attorney for Applicants  
Reg. No. 44,923

Texas Instruments Incorporated  
P.O. Box 655474, MS 3999  
Dallas, TX 75265  
(972) 917-4258

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ATTORNEY: PKM  
DOCKET NO: TI-36640  
DATE: 12-16-4  
DUE DATE: 12-17-4

*TEXAS INSTRUMENTS  
PATENT DRAFTING*

972-917-5639

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